

In re Application of:

HITOSHI NAKANO

Application No.: 09/536,637

Filed: March 28, 2000

For: APPARATUS WITH AIR-CONDITIONING
SYSTEM, AND DEVICE MANUFACTURING
METHOD USING THE SAME

COMMISSIONER FOR PATENTS
BOX AF
Washington, D.C. 20231



Docket No.: 00684.002985

AFY/H
3743

Examiner: L. Ceric

Group Art Unit: 3743

Date: April 26, 2002

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TECHNOLOGY CENTER 3700

Sir:

Transmitted herewith is an Amendment After Final Rejection in the above-identified application.

No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	18	MINUS	20	= 0	x \$9 \$18	\$ -0-
INDEP. CLAIMS	2	MINUS	3	= 0	x \$42 \$84	\$ -0-
Fee for Multiple Dependent claims \$140°/\$280						
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT---						\$ -0-

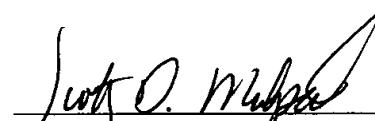
°Verified Statement claiming small entity status is enclosed, if not filed previously.

A check in the amount of \$____ is enclosed.

Charge \$____ to Deposit Account No. 06-1205. A duplicate copy of this sheet is enclosed.

- Any prior general authorization to charge an issue fee under 37 C.F.R. 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 C.F.R. 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate copy of this paper is enclosed.
- A check in the amount of \$ 110.00 to cover the fee for a ONE month extension is enclosed.
- A check in the amount of \$ to cover the Information Disclosure Statement fee is enclosed.
- Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicant

Registration No. 32,533

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SDM\mm

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Approved
JVC
5-8-02

684.2985



PATENT APPLICATION

LD
5-20-02
PL3

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
HITOSHI NAKANO) Examiner: L. Ceric
Application No.: 09/536,637) Group Art Unit: 3743
Filed: March 28, 2000)
For: APPARATUS WITH AIR-) April 26, 2002
CONDITIONING SYSTEM, AND)
DEVICE MANUFACTURING)
METHOD USING THE SAME)

Commissioner for Patents
Washington, D.C. 20231

REQUEST TO MAKE DRAWING CHANGES

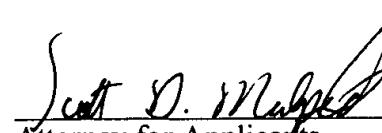
Sir:

Enclosed, in accordance with U.S. Patent and Trademark Office Practice, are copies of proposed drawing changes shown in red ink, wherein Figure 1 is amended to locate the semiconductor manufacturing equipment, the inspection equipment and measuring equipment within chamber 1.

Approval of the drawing corrections by the Examiner is respectfully requested.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our below-listed address.

Respectfully submitted,



Attorney for Applicants

Registration No. 32,533

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